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APPLICANTS

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** CONTINUING DATA ***** NONE *LV*

** FOREIGN APPLICATIONS ***** *YF* *LV*
 JAPAN 2002-310257 10/24/2002

IF REQUIRED, FOREIGN FILING LICENSE GRANTED
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Foreign Priority claimed 35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance	STATE OR COUNTRY JAPAN	SHEETS DRAWING 9	TOTAL CLAIMS 95	INDEPENDENT CLAIMS 13
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Verified and Acknowledged
 Examiner's Signature *LV* Initials *LV*

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 26171
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TITLE
 Method for cleaning plasma etching apparatus, method for plasma etching, and method for manufacturing semiconductor device

FILING FEE RECEIVED 2980	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue)
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